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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/809,006	03/24/2004	Ranganathan Nagarajan	33726-00016USD1	6795
23932	7590 09/28/2005		EXAMINER	
JENKENS & GILCHRIST, PC			ALANKO, ANITA KAREN	
1445 ROSS A SUITE 3200	VENUE		ART UNIT	PAPER NUMBER
DALLAS, TX	75202		1765	

DATE MAILED: 09/28/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)
Office Action Summary		10/809,006	NAGARAJAN, RANGANATHAN
		Examiner	Art Unit
		Anita K. Alanko	1765
Period f	The MAILING DATE of this communication aport	pears on the cover sheet with the o	correspondence address
A SH WHIII - Extending aftender - If No - Fail Any	IORTENED STATUTORY PERIOD FOR REPLICATION OF THE MAILING DEPOSITION OF	DATE OF THIS COMMUNICATION 136(a). In no event, however, may a reply be tire I will apply and will expire SIX (6) MONTHS from the, cause the application to become ABANDONE	N. mely filed the mailing date of this communication. ED (35 U.S.C. § 133).
Status			
2a) <u></u>	Responsive to communication(s) filed on 3/24 This action is FINAL . 2b) This Since this application is in condition for allowed closed in accordance with the practice under	s action is non-final. ance except for formal matters, pro	
Disposit	ion of Claims		
5)	Claim(s) 1-19 is/are pending in the application 4a) Of the above claim(s) is/are withdrated claim(s) is/are allowed. Claim(s) 1-19 is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/or is/are specification is objected to by the Examinating The drawing(s) filed on is/are: a) accomplicant may not request that any objection to the Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) including the correct the oath or declaration is objected to by the Examinating sheet(s) in the oath of th	er. cepted or b) objected to by the edrawing(s) be held in abeyance. Section is required if the drawing(s) is objected.	e 37 CFR 1.85(a). ejected to. See 37 CFR 1.121(d).
Priority	under 35 U.S.C. § 119		•
a)	Acknowledgment is made of a claim for foreign All b) Some * c) None of: 1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority application from the International Bureasee the attached detailed Office action for a list	its have been received. Its have been received in Applicationity documents have been received in (PCT Rule 17.2(a)).	ion No. <u>09/900293</u> . ed in this National Stage
2) 🔲 Notic 3) 🔲 Infor	et(s) te of References Cited (PTO-892) te of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08 ter No(s)/Mail Date	4) Interview Summary Paper No(s)/Mail Da) 5) Notice of Informal P 6) Other:	

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Claim Rejections - 35 USC § 112

The following is a quotation of the first paragraph of 35 U.S.C. 112:

The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.

Claim 5 is rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the enablement requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention. There appears to be no description of the "pulsed etch process". Virtually any parameter could be pulsed, the source power, bias power, gas composition, pressure, gas flow or magnetic field. Lacking any description or working examples, the specification does not enable one to make and use the claimed invention of "pulsed etch process".

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

Claim 5 is rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. It is unclear what is encompassed by "pulsed etch process" and therefore the metes and bounds of the claim are unclear.

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 1-5, 7-8, 10, 14-17 and 19 are rejected under 35 U.S.C. 102(b) as being anticipated by Berglund et al (US 4,902,377).

Berglund discloses a method comprising:

performing a vertical etch process step on said layer of material 12 (Fig.2)

enlarging the opening in said mask (the "mask erosion step" Fig.3); and

repeating steps a and b above in an alternating manner until a trench has been etched to a desired depth.

As to claims 2 and 16, Berglund discloses a resist etch process step to enlarge the opening (col.3, lines 28-41).

As to claims 3 and 17, the resist layer is inherently tapered around a periphery of said opening since the resist layer is isotropically etched (col.3, lines 29-31).

As to claim 4, Berglund discloses that it is a multistep process (col.3, lines 56-57).

As to claims 5 and 14, broadly interpreted, the method of Berglund is a pulsed etch process since Berglund discloses to perform the steps "in the same machine by altering the gas types, gas concentrations and operating pressure during the etch process" multiple times (col.3, lines 52-56). The alternation of steps encompasses controlling gas flow, as broadly cited.

As to claims 7 and 19, since the same steps are conducted as in the instant invention, the same results of a slope within the cited range are expected.

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As to claim 8, Berglund discloses that the method comprises a semiconductor substrate 21.

As to claim 10, Berglund discloses to perform a metal deposition 18 (Fig.5).

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 6-7, 9, 11-13, 18-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Berglund et al (US 4,902,377).

The discussion of Berglund from above is repeated here.

As to claims 6 and 18, Berglund does not disclose the depth of the trench. It would have been obvious to one with ordinary skill in the art to repeat the steps to the desired depth within the cited range because Berglund discloses to repeat the steps as often as desired. Examiner notes that the claims are not limited to a particular aspect ratio.

As to claims 7 and 19, it would have been obvious to one with ordinary skill in the art to vary the sizes of the mask openings and the etching parameters, and thereby the slope to the cited range, in the method of Berglund because the mask and concentration and energy of etchant species define how much material can be removed by etching, and therefore helps define the slope.

As to claims 11-13, examiner takes official notice that the cited devices are conventional devices that are formed by using conventional semiconductor etching techniques. It would have been obvious to one with ordinary skill in the art to use the method of Berglund to form the cited devices because it is useful to use known semiconductor processing techniques to form the cited known devices.

Conclusion

The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. The cited art shows method of forming tapered trenches.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Anita K. Alanko whose telephone number is 571-272-1458. The examiner can normally be reached on Mon-Fri until 2:30 pm (Wed until 11:30).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on 571-272-1465. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Anita K. Hanko Anita K Alanko Application/Control Number: 10/809,006

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